

| Comparison of Klocke Nanotechnik Nanorobotics manipulators with other manipulators | | High Performance Nanorobotics | Low-Cost Nanorobotics | Tilting device | Hybrid drives |
|---|--|--------------------------------------|------------------------------|-----------------------|----------------------|
| 1 | Cartesian movement of independent axes (important for an easy operation) | Yes | Yes | No | Yes |
| 2 | Absolute positioning vertical axis (in the "blind" direction of a SEM), repeatability better 60 nm | Yes | Yes | No | No |
| 3 | Optional position sensors also for XY axes, repeatability better 60 nm | Yes | No | No | No |
| 4 | Small design (to fit in any chamber) | Yes | Yes | Yes | No |
| 5 | Many options to fix tools easily | Yes | Yes | No | Yes |
| 6 | Robust (crash resistant) | Yes | Yes | No | Yes |
| 7 | Movable (by hand or by collisions) without losing the position information | Yes | No | No | No |
| 8 | Pure piezo drive from nm to cm stroke and not an electro motor coupled with a piezo | Yes | Yes | Yes | No |
| 9 | Resolution of single Nanometers | Yes | Yes | Yes | No |
| 10 | A real fine positioning stroke of at least 1 micron | Yes | Yes | Yes | No |
| 11 | Vibrations of the whole manipulator below 10 nm | Yes | Yes | Yes | No |
| 12 | Stroke selectable in a range between 5 and 50 mm | Yes | No | No | Yes |
| 13 | Modular design to choose size and stroke for each axis | Yes | No | No | No |
| 14 | Stationary assembly designed => sample can move independent from manipulator. If necessary also movable with sample stage | Yes | Yes | No | No |
| 15 | "Micro-Jackhammer" mode (with e.g. 50 G accelerations) to process material | Yes | Yes | Yes | No |
| 16 | Network Electronics with external intelligence to ease the attachment to any SEM or FIB | Yes | Yes | No | No |
| 17 | Secure approach of the sensor/actuator by different probe techniques | Yes | No | No | No |
| 18 | Force Feedback option including electronics and software | Yes | Yes | No | No |
| 19 | Assembly of a series of different Microgrippers | Yes | Yes | No | No |
| 20 | Upgrade to form Wafer Probing Systems available | Yes | No | No | Yes |
| 21 | Option as Micro Tensile Machine available | Yes | Yes | No | No |
| 22 | Upgrade to form the first real Dimensional SEM/FIB with nm precision available | Yes | No | No | No |
| 23 | Option of Vision System for pattern recognition available | Yes | Yes | No | No |
| 24 | Plenty expendable items available: Small sensors and actuators including adapters | Yes | No | No | No |
| 25 | Compatible absolute positioning sample stages available, to form complete systems | Yes | Yes | No | Yes |
| 26 | Software on three levels: DLL, Manual Control (keypad, force feedback joystick) and Automation by Macros & Process Control Sequencer | Yes | No | No | No |
| TOTAL YES: | | 26 | 17 | 6 | 6 |
| "Performance factor": | | > 4 / 1 | | | |
| "Price factor for comparable items": | | << 4 / 1 | | | |